Abstract

Method for the optical inspection of a transparent protective layer and of a colored patterned surface

With a method for the optical inspection of a transparent protective layer (14) and of a colored patterned surface, whereby the transparent protective layer (14) at least partially covers the colored patterned surface, and a first source of illumination (40) and an imaging sensor (42) associated with the first source of illumination (40) are provided, the protective layer (14) is illuminated with the light emitted by the source of illumination (40) in order to recognize defective places (30) inside and beneath the transparent protective layer (14). The first source of illumination (40) emits light in the shortwaved visible range and the light striking the surface penetrates at least partially into the protective layer (14) and is scattered at the defective places (30). Light scattered back from the defective places (30) is picked up by the imaging sensor (42) and the defective places (30) are recognized by the local increase in the intensity of the light picked up by the imaging sensor (42) in the area of the defective places (30).

(Figure 3)

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